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On

July 2, 2002  
TOWNSEND and TOWNSEND and CREW LLP

By: *Andrew*

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**RESPONSE TO OFFICE ACTION  
UNDER 37 CFR 1.116 EXPEDITED  
PROCEDURE - EXAMINING GROUP  
1763**

**PATENT**

Attorney Docket No.: 1084D01T93200  
TTC No.: 16301-009320

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re application of:

David Cheung et al.

Application No.: 09/418,818

Filed: October 15, 1999

For: METHOD AND APPARATUS FOR  
DEPOSITING ANTIREFLECTIVE  
COATING

Examiner: Rudy Zervigon

**RESPONSE TO OFFICE ACTION UNDER  
37 CFR 1.116 EXPEDITED PROCEDURE  
EXAMINING GROUP 1763**

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**Box AF**  
Assistant Commissioner for Patents  
Washington, D.C. 20231

Sir:

In response to the Final Office Action mailed May 2, 2002, please reconsider this application in view of the following comments.

**IN THE CLAIMS:**

The claims are unamended, but are reproduced below for the Examiner's convenience and reference.

1. A substrate processing system, comprising:  
a vacuum chamber;